



## Development and Commissioning of the Highly Granular Scintillator-based Calorimeters of CEPC

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#### **On behalf of CEPC Calorimeter working group**













### **CEPC** brief introduction and particle flow algorithm

- Circular Electron Positron Collider(CEPC)
  - Future lepton collider as Higgs/W/Z factories
  - Precision measurements of the Higgs/EW/QCD
  - ➤ Calorimetry requirement: 3-4% boson mass resolution for W/Z hadronic decays  $\rightarrow$  30%/ $\sqrt{E}$  jet resolution
- Particle flow algorithm(PFA)
  - Use optimal sub-detectors to measure energy/momentum of secondary particles in a jet
    - $\square$  ~60%  $E_{jet}$  : charged particles measured by tracker
    - $\square$  ~30%  $E_{jet}$  : photons measured by ECAL
    - $\square \sim 10\% E_{jet}$  : neutral hadrons measured by HCAL
  - ➤ Separation of close-by particles in jet → high granularity calorimeters
  - This talk focus on following high-granularity calorimeters
    - Scintillator-tungsten ECAL prototype
    - Scintillator-steel AHCAL prototype





#### Scintillator-tungsten ECAL prototype(ScW-ECAL)







Plastic scintillator strips with ESR film on PCB board

Aluminium frame

- ScW-ECAL technological prototype
  - Plastic scintillator strips(45×5×2 mm<sup>3</sup>) + WCu(85:15) absorber + Hamamatsu S12571-010, S12571-015 SiPMs
  - > Sensitive area :  $22x22 \ cm^2$ , 32 layers in longitudinal dimension(~22.4 $X_0$ )
  - > Orthogonal placement of two adjacent layers for almost  $5x5 mm^2$  granularity
  - ➢ 6920 channels, 192 SPIROC2E electronics chips, ~350kg



#### **Scintillator-steel AHCAL prototype**



AHCAL technological prototype

- AHCAL technological prototype
  - Plastic scintillator tiles (40×40×3 mm<sup>3</sup>) + steel absorber plates + Hamamatsu S14160-1315PS and NDL 22-15 SiPMs
  - > Sensitive area : 72x72  $cm^2$ , 40 layers in longitudinal dimension (~4.6 $\lambda_I$ )
  - > 12960 channels, 360 SPIROC2E chips, ~5 ton



AHCAL basic unit design



PCB, 2.5 mm

Scintillator, 3.5 mm

2024-10-23

#### **CERN** beamtests in 2022-2023





Supporting table for alignment of ECAL and AHCAL transverse sensitive area and adjustment of beam position

Beamtest @PS T9

#### Data taking overview



- Decent statistics of beamtest data samples (~63M events in total)
  - Muons: 10 GeV (PS-T9), 108/160 GeV (H8), 100/120 GeV (H2);
  - Electrons/positrons: 0.5 5 GeV at PS; 10 250 GeV at SPS;
  - ➢ Pions: 1 15 GeV at PS, 10 120 GeV (also 150 350 GeV) at SPS



#### **Pedestal calibration**

- Pedestal acquisition
  - Multi-peaks pedestal distribution due to crosstalk
  - Channel-level pedestal from force-trigger mode file
- Stable pedestal during beamtest
  - Pedestal mean : 280~550 ADC for both ECAL and AHCAL pedestal sigma : 1~6 ADC for both ECAL and AHCAL
  - > 0~2 ADC fluctuation in both SPS and PS TB

Pedestal changes when beamtest condition changes









### **ASIC** chip gain calibration

- Large dynamic range: high-gain/low-gain mode on SPIROC2E
- SPIROC2E chip gain: high-gain/low-gain ratio calibration
  - Datasets selection: e- for ECAL, pi- for AHCAL
  - Linear fit range limits: ECAL(300, max-600), HCAL(200, max-500)
  - SPIROC2E chip gain: high-low gain ratio 30~40
- Dead channel monitor
  - ECAL: 64 dead channels, less than 3%
  - AHCAL: less than 10 dead channels





AHCAL: ASIC gain overview



#### **MIP** calibration

- 100GeV muon file as datasets with position scan
- Track fit to exclude the dark noise
- Landau convoluted gaussian function
- MIP calibration monitor
  - ECAL: 68.9% channels calibrated successfully
  - > AHCAL: 93.3% channels calibrated successfully





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#### AHCAL: MIP spectrum of 15um-SiPM Hamamatsu channel



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### SiPM gain calibration

- SiPM gain calibration for MC digitization
  - Multiple APD pixels operating in Geiger mode
  - SiPM response non-linearity correction

 $N_{fired} = N_{pixel} \cdot (1 - e^{-\frac{N_{seed}}{N_{pixel}}})$ ,  $N_{seed} = N_{photon} \times PDE$ 

- SiPM gain calibration: LED data during TB
  - Single photoelectron spectrum with multigaussian peaks
    - $\square Peak number \rightarrow photoelectron number$
    - $\square \text{ Peak interval} \rightarrow \text{SiPM gain}$
  - Linear fit of the peak position: SiPM gain determined by slope







#### AHCAL: Peak position linear fit





### Simulation and digitization

- Geant4 simulation: standalone ScW-ECAL and AHCAL prototypes' geometry
- Digitization: Improvement on consistency of MC/data
  - $\blacktriangleright$  Energy deposition in Geant4  $\rightarrow$  ADC counts in electronics
    - Scintillation process: Energy deposition → photon number (SiPM gain, MIP MPV)
    - □ SiPM response: Photon number → fired pixel number (sampling model to do SiPM saturation correction)
    - $\blacksquare$  Electronics: fired pixel number  $\rightarrow$  ADC counts (Pedestal , ASIC chip gain)





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Beam Energy(GeV)

### AHCAL response data/MC comparison

<u>×1</u>0<sup>3</sup>

MC truth

- MC diai

250

data

1.8

1.6

1.4+

.2

0.8 0.6

0.4

0.2

200

**Event Number** 

- Beam purity study: fractal dimension(FD) and • Artificial Neural Network (ANN)
- AHCAL prototype data/MC comparison ۲
  - Event selection applied on data file analysis
  - MIP spectrum data/MC crosscheck: slight difference  $\geq$
  - $\geq$ Electron datasets (1-50GeV) :~10% discrepancy





#### AHCAL performance preliminary results



- Pion datasets: 10-80GeV with event selection
  - > Energy linearity is within  $\pm 1.5\%$  (expected 3%)
  - Energy resolution:  $\frac{56.2\%}{\sqrt{E(GeV)}} \oplus \frac{2.9\%}{2.9\%}$  (expected  $\frac{60\%}{\sqrt{E(GeV)}} \oplus \frac{3\%}{2.9\%}$ )  $\triangleright$



80



### Summary and prospects



- High granularity calorimeter is the baseline option of CEPC
- Development of Scintillator-based tungsten ECAL and steel AHCAL prototype
- Successful beamtests campaigns at CERN SPS/PS during 2022-2023
  > Huge amount data samples cover wide energy range including various particle species
- Preliminary analysis results of calorimeters
  - Fundamental parameters calibration and stability check
  - > Optimization of prototype simulation and digitization for validation between data/MC samples
  - > Calorimeters performance analysis: AHCAL performance reach the design requirements
- Future
  - Ongoing analysis activities
    - □ ScW-ECAL prototype performance study
    - □ Improvement on data/MC consistency
  - ECAL and AHCAL combined analysis
    - □ PFA performance study

### Summary and prospects



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    - □ Improvement on data/MC consistency: SiPM/ASIC non-linearity
  - ECAL and AHCAL combined analysis
    - □ PFA performance study





# Backup



#### ECAL SiPM

关键参数	S12571-010P	S12571-015P	
灵敏面积	$1 mm \times 1 mm$	$1 \ mm  imes 1 \ mm$	
封装尺寸	$1.9\ mm  imes 2.4\ mm$	$1.9\ mm \times 2.4\ mm$	
像素数量	10000	4489	
像素尺寸	$10 \ um$	$15 \ um$	
增益	$1.35 \times 10^{5}$	$2.3 \times 10^5$	
最灵敏波长	$470 \ nm$	$460 \ nm$	
光探测效率	10~%	25~%	
暗计数	$100 \ kHz$	$100 \ kHz$	
串扰率	$\sim 7\%$	$\sim 13\%$	
推荐电压	击穿电压 +4.5 V	击穿电压 +4 V	

Company	NDL	НРК
Туре	22-15	S14160-1315PS
Sensitive area (mm <sup>2</sup> )	1.6*4	1.69
PDE (%)	40	32
Gain (*10⁵)	2.4	3.6
Pixel No.	7400*4	7284
Breakdown Voltage (V)	19	38
OverVoltage (V)	4	4
Dark Count (kHz)	330*4	120
Cross Talk (%)	8.5	1.0

AHCAL SiPM

#### **Pedestal issue**



- Self-trigger mode, DAC calibration
- Inject DAC(50, 100, 200, 300, 400) into channel 0, and observe the signal in channel 1



• guess : crosstalk may exist in some chips and crosstalk will change

#### Photon generating process



- Photon number
  - >  $E_{MIP} = E_{Truth} / 0.305 \text{ MeV}$ > p.e. =  $E_{MIP} / \text{light yield}(p.e./MIP)$ > photon = p.e./PDE
- Poisson smear
- Non-uniformity of light output(~4.2%)





Parameter		Symbol	S12571-010P	S12571-015P	Unit
Spectral response range		λ	320 to 900	320 to 900	nm
Peak sensitivity wavelength		λp	470	460	nm
Photon detection efficiency $(\lambda = \lambda p)^{*4}$		PDE	10	25	%
Dark count*5	Typ.		100	100	kcps
	Max.		200	200	
Time resolution (FWHM)*6			300	250	ps
Terminal capacitance		Ct	35	35	pF
Gain		M	1.35 × 105	2.3 × 10 <sup>5</sup>	-
Gain temperature coefficient		ΔΤΜ	1.6 × 10 <sup>3</sup>	3.5 × 10 <sup>3</sup>	/°C
Breakdown voltage		VBR	65 ± 10	65 ± 10	V
Recommended operating voltage		Vop	VBR + 4.5	VBR + 4.0	V
Temperature coefficient of recommended operating voltage		∆TVop	60	60	mV/°C



#### SiPM model: SiPM pixel saturation

- Hamamatsu SiPM S12571-010P, S12571-015P
  > 10000(100\*100), 4489(67\*67) pixels respectively
  > ~ 8 , 22 p.e./MIP
- SiPM saturation model
  - Uniform sampling a pixel from pixel array
  - Binomial sampling for PDE
  - ➢ IF NOT avalanche, then let it avalanche
  - Get total fired pixel number





End

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- Hamamatsu SiPM S12571-010P, S12571-015P •
  - Optical crosstalk may not be ignored

$$P_{CT} = (N_{2p.e.} + N_{3p.e.} + N_{4p.e.} + ...)/(N_{1p.e.} + N_{2p.e.} + N_{3p.e.} + ...)$$

- **Crosstalk Model** •
  - ➤ 100\*100 , 67\*67 pixel placement
  - Uniform sampling a neighboring pixel from eight directions
  - > Set  $P_{CT}$  as probability of optical crosstalk occurs in one of neighboring pixel







pixel\_pt\_0.10

#### SiPM model: SiPM crosstalk





#### **ADC** conversion



- ADC && gaussian smear
  > ADC Mean = N<sub>p.e.</sub> \* SiPM Gain
  > ADC Sigma = 3 \* sqrt(N<sub>p.e.</sub>)
- High-low gain mode ADC
- Pedestal fluctuation
- High-low gain saturation
  - $\succ$  High gain saturation: high adc > switch point , let high adc =4000
  - Low gain saturation : low adc > 3000, let low adc = 3000

